

CLAIMS

1. A management system for a semiconductor fabrication apparatus composed of a plurality of integrated components, wherein

a manager terminal used by a manager managing the semiconductor fabrication apparatus and an information processor configured to hold component information on the semiconductor fabrication apparatus are communicably configured via a network,

the manager terminal includes

a capturing means configured to capture the semiconductor fabrication apparatus,

a component information receiving means configured to receive component information on the semiconductor fabrication apparatus from the information processor,

an identification processing means configured to identify a position of a component constituting the semiconductor fabrication apparatus on a captured image of the semiconductor fabrication apparatus,

a compositing processing means configured to create a composite image in which component information on the identified component is composited with a captured image of the semiconductor fabrication apparatus at a position of the identified component, and

an image display means configured to display the composite image, and

the information processor includes

a component information storing means configured to store component information on a component constituting the semiconductor fabrication apparatus,

an extraction processing means configured to make reference to the component information storing means to extract the component information, and

a component information transmitting means configured to transmit the component information to the manager terminal.

2. The management system for a semiconductor fabrication apparatus according to claim 1, wherein

on the semiconductor fabrication apparatus, a marker is attached at a predetermined place,

the identification processing means identifies a position of a component constituting the semiconductor fabrication apparatus on the captured image of the semiconductor fabrication apparatus based on relative coordinates of components relative to the attachment place of the marker, and

the component information storing means further stores information relating to relative coordinates of components relative to the attachment place of the marker as component

information.

3. The management system for a semiconductor fabrication apparatus according to claim 1, wherein

the semiconductor fabrication apparatus has a predetermined identification label attached to four or more components,

the identification processing means identifies a position of a component constituting the semiconductor fabrication apparatus on the captured image of the semiconductor fabrication apparatus based on relative coordinates of respective components relative to the attachment place of the identification label, and

the component information storing means further stores information relating to relative coordinates of respective components relative to the attachment place of the identification label as component information.

4. The management system for a semiconductor fabrication apparatus according to claim 1, wherein

the management system is communicably configured with the semiconductor fabrication apparatus via a network,

the semiconductor fabrication apparatus has

a sensing information transmitting means configured to transmit sensing information obtained by sensing operation status of respective components on the information processor, and

the information processor further has

a sensing information receiving means configured to receive the sensing information from the semiconductor fabrication apparatus, and

a first registration means configured to make reference to the component information storing means to register the sensing information as the component information.

5. The management system for a semiconductor fabrication apparatus according to claim 1, wherein

the manager terminal further has

an input means configured to accept an input of additional information specifying a predetermined component on the composite image from the manager, and

an additional information transmitting means configured to transmit the inputted additional information to the information processor together with specification of the predetermined component, and

the information processor further has

a second registration means configured to make reference to the component information storing means to register the additional information as the component information.

6. The management system for a semiconductor fabrication apparatus according to claim 1, wherein

the manager terminal further has

an image control means configured to detect an amount of movement according to movement of the manager terminal to control the composite image according to the amount of movement.

7. The management system for a semiconductor fabrication apparatus according to claim 1, wherein

the manager terminal further has

a recording means configured to record a task by the manager based on the composite image.

8. A management method for a semiconductor fabrication apparatus composed of a plurality of integrated components, wherein

in a system in which a manager terminal used by a manager managing the semiconductor fabrication apparatus and an information processor including a component information storing means configured to store component information on a component constituting the semiconductor fabrication apparatus are communicably configured via a network,

the manager terminal executes

a capturing process of capturing the semiconductor fabrication apparatus,

a component information receiving process of receiving component information on the semiconductor fabrication apparatus from the information processor,

an identifying process of identifying a position

of a component constituting the semiconductor fabrication apparatus on the captured image of the semiconductor fabrication apparatus,

a compositing process of a creating a composite image in which component information on the identified component is composited with the captured image of the semiconductor fabrication apparatus at a position of the identified component, and

an image display process of displaying the composite image, and

the information processor executes

an extracting process of making reference to the component information storing means to extract the component information, and

a component information transmission process of transmitting the component information to the manager terminal.

9. A computer program stored on a non-transitory computer-readable medium for managing a semiconductor fabrication apparatus composed of a plurality of integrated components, wherein

in a system in which a manager terminal used by a manager managing the semiconductor fabrication apparatus and an information processor including a component information storing means configured to store component information on a component constituting the semiconductor fabrication

apparatus are communicably configured via a network,

the computer program causes the manager terminal to execute

a capturing process of capturing the semiconductor fabrication apparatus,

a component information receiving process of receiving component information on the semiconductor fabrication apparatus from the information processor,

an identifying process of identifying a position of a component constituting the semiconductor fabrication apparatus on the captured image of the semiconductor fabrication apparatus,

a compositing process of a creating a composite image in which component information on the identified component is composited with the captured image of the semiconductor fabrication apparatus at a position of the identified component, and

an image display process of displaying the composite image, and

the computer program causes the information processor to execute

an extracting process of making reference to the component information storing means to extract the component information, and

a component information transmission process of

transmitting the component information to the manager terminal.